

Transparent and conductive Pd-C nanostructural films

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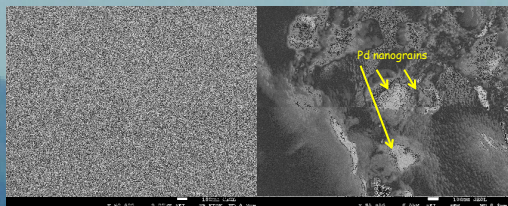
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INTRODUCTION

Transparent conducting films have been studied extensively because of their broad range of application such as transparent electrodes in display, in photovoltaic devices and optoelectronic systems.

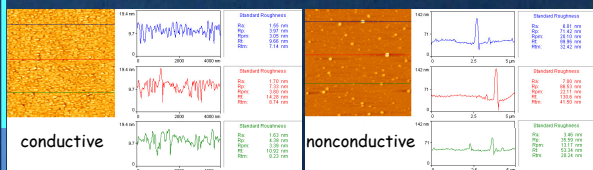
In this presentation we want to present carbonaceous-palladium films (C-Pd films) deposited on glassy or fused silica substrates. These films were obtained by two ways; first method was PVD process. Second method was PVD process followed by pyrolytic CVD process under influence of xylene. In PVD process we use two separated sources containing fullerenes and palladium acetate. In CVD process we were modifying C-Pd films prepared by PVD. Obtained films were characterized by SEM (topography and morphology), AFM (topography) and adhesion, resistivity and by UV-VIS- FTIR absorption spectroscopy.

SEM



SEM images of PVD C-Pd film and CVD/PVD C-Pd film

AFM



Average roughness

1.55nm

3.1nm

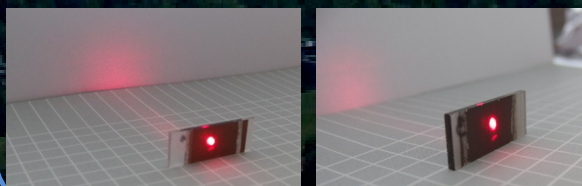
Properties of prepared C-Pd films

Sample no	Pd content Wt %	C-Pd film resistivity [kOhm cm]	Film thickness [nm]
PVD1	16	18	300
PVD2	~10	nonconductive	300
CVD/PVD1	-	14	>> 400nm
CVD/PVD2	-	6000	>> 400nm

Transparency of C-Pd film deposited on fused silica for $\lambda = 650 - 20\text{nm}$ laser line

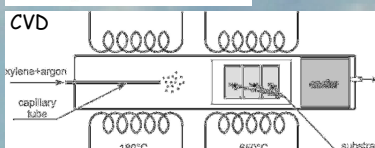
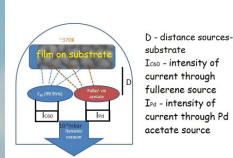
PVD C-Pd film
resistivity $\rho = 18\text{ k}\Omega\text{ cm}$

CVD/PVD C-Pd film
nonconductive



TECHNOLOGY

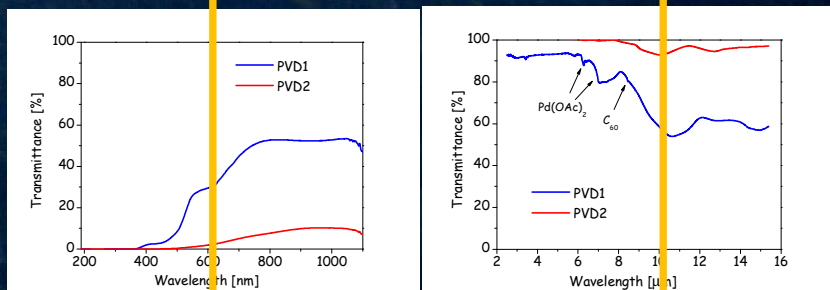
PVD



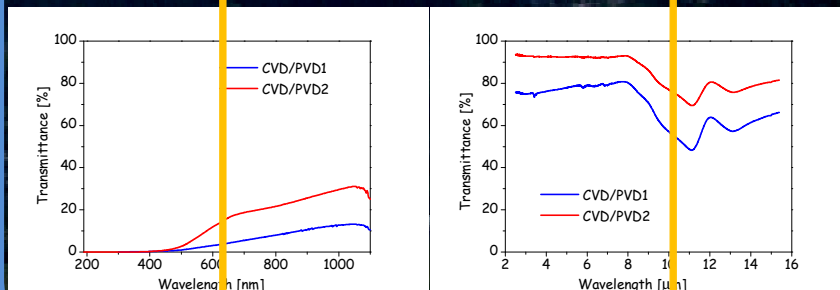
Sample no	I Pd [A]	I C60 [A]	D [mm]	Time [min]	Film thickness [nm]
PVD1	1	2	60	5	300
PVD2	1.2	2.1	69	8	300

Sample no	I Pd [A]	I C60 [A]	D _{C60} [mm]	Time [min]
PVD1	2.1	1.3	54	10
PVD2	2.1	1.3	77	10
	Xe flow [ml/min]	Ar flow [ml/min]	Temperature [K]	Time [min]
CVD/PVD1	0.1	3	923	30
CVD/PVD2	0.1	3	923	30

UV-VIS and FIR transmittance



Transmittance window



Non-conductive

Conclusions

1. Films obtained by PVD and CVD processes are transparent in the visible and near-infrared regions (up to 1100 nm) and have low resistivity.

2. The work was supported by the Polish Ministry of Science and Higher Education, the Ministry of Economy and Regional Development, the Ministry of National Education and Science.